



DEP & REF

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Konstantin Holdermann

Confirmation No.7688

Application No. : 10/090,915

Filed : March 5, 2002

Title : ETCHING SOLUTION FOR WET CHEMICAL PYRAMIDAL
TEXTURE ETCHING OF SILICON SURFACES

Grp./Div. : 1765

Examiner : Shamim Ahmed

Docket No. : 47585/RAG/S969

REQUEST FOR REFUND

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Post Office Box 7068
Pasadena, CA 91109-7068
August 11, 2005

Commissioner:

The Notice of Allowance for the above-identified application was vacated on May 3, 2005, and a new Office action was issued on the same date. Accordingly, Applicant hereby requests a refund of the issue fee in the amount of \$1370.00. In the newly issued Office action, Applicant was advised of its ability to request a refund of the issue fee, which it paid on December 2, 2004.

Applicant hereby requests that the refund amount of \$1370.00 be credited to deposit account 03-1728, show its reference number (S969:47585). A copy of this request is enclosed.

Respectfully submitted,

CHRISTIE, PARKER & HALE, LLP

By 

Robert A. Green
Reg. No. 28,301
626/795-9900

RAG/ldb

Enclosure: Copy of this request
LDB PAS637395.1-08/10/05 10:43 AM

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 8/11/05

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